

PATENT/OFFICIAL

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Young Joseph PAIK

Serial No. 09/998,384

Filed: November 30, 2001

Group Art Unit: 2812

Examiner:

For: FEEDFORWARD AND FEEDBACK CONTROL FOR CONDITIONING OF  
CHEMICAL MECHANICAL POLISHING PAD

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

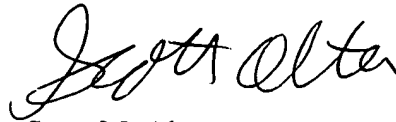
**Serial No. 09/998,384**

to present to the Office the relevant facts and law regarding the appropriate status of such document.

Please charge the fee of \$180.00 under 37 CFR 1.17(p) to Deposit Account No. 08-0219. The Commissioner is authorized to charge any deficiency in any fees pursuant to 37 CFR § 1.17 associated with this communication and to credit any excess payment to Deposit Account No. 08-0219.

Respectfully submitted,

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<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (PTO-1449)				ATTY. DOCKET NO. 005916 USA/ FPS/MMCS/MC		SERIAL NO. 09/998,384	
				APPLICANT Young Joseph PAIK			
				FILING DATE November 30, 2001		GROUP 2812	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,975,994	11/02/99	Sandhu et al.			06/11/97	
	6,113,462	09/05/00	Yang			12/18/97	
	6,230,069 B1	05/08/01	Campbell et al.			06/26/98	
	6,268,270 B1	07/31/01	Scheid et al.			10/29/99	
	6,277,014 B1	08/21/01	Chen et al.			10/09/98	
	6,291,367 B1	09/18/01	Kelkar			06/01/00	
	6,465,263 B1	10/15/02	Coss, Jr. et al.			01/04/00	
	6,532,555 B1	03/11/03	Miller et al.			10/29/99	
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	6,541,401 B1	04/01/03	Herner et al.			07/31/00	
	6,546,508 B1	04/08/03	Sonderman et al.			10/29/99	
	6,556,881 B1	04/29/03	Miller			09/09/99	
	6,652,355 B2	11/25/03	Wiswesser et al.			06/04/01	
	6,725,402 B1	04/20/04	Coss, Jr. et al.			07/31/00	
EXAMINER				DATE CONSIDERED			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

<p style="text-align: center;"><b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b></p> <p style="text-align: center;">(PTO-1449)</p> 	<p>ATTY. DOCKET NO. 005916 USA/ FPS/MMCS/MC</p>	<p>SERIAL NO. 09/998,384</p>
	<p>APPLICANT Young Joseph PAIK</p>	
	<p>FILING DATE November 30, 2001</p>	<p>GROUP 2812</p>
<p style="text-align: center;"><b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b></p>		
	<p>IslamRaja, M. M., C. Chang, J. P. McVittie, M. A. Cappelli, and K. C. Saraswat. May/June 1993. "Two Precursor Model for Low-Pressure Chemical Vapor Deposition of Silicon Dioxide from Tetraethylorthosilicate." <i>J. Vac. Sci. Technol. B</i>, Vol. 11, No. 3, pp. 720-726.</p>	
	<p>Kim, Eui Jung and William N. Gill. July 1994. "Analytical Model for Chemical Vapor Deposition of SiO<sub>2</sub> Films Using Tetraethoxysilane and Ozone" (Abstract). <i>Journal of Crystal Growth</i>, Vol. 140, Issues 3-4, pp. 315-326.</p>	
	<p>Guo, R.S, A. Chen, C.L. Tseng, I.K. Fong, A. Yang, C.L. Lee, C.H. Wu, S. Lin, S.J. Huang, Y.C. Lee, S.G. Chang, and M.Y. Lee. June 16-17, 1998. "A Real-Time Equipment Monitoring and Fault Detection System." <i>Semiconductor Manufacturing Technology Workshop</i>, pp. 111-121.</p>	
	<p>Lantz, Mikkel. 1999. "Equipment and APC Integration at AMD with Workstream." <i>IEEE</i>, pp. 325-327.</p>	
	<p>July 15, 2004. Office Action for U.S. Serial No. 10/172,977, filed June 18, 2002.</p>	
	<p>August 2, 2004. Office Action for U.S. Serial No. 10/174,377, filed June 18, 2002.</p>	
	<p>August 9, 2004. Written Opinion for PCT Serial No. PCT/US02/19063.</p>	
	<p>August 18, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/19116.</p>	
	<p>August 24, 2004. Office Action for U.S. Serial No. 10/135,405, filed May 1, 2002.</p>	
	<p>September 9, 2004. Written Opinion for PCT Serial No. PCT/US02/21942.</p>	
	<p>September 16, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/24859.</p>	
EXAMINER	DATE CONSIDERED	

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